

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: C. Saloma et al.

Serial No. : Not Yet Assigned

For: METHOD FOR GENERATING HIGH-CONTRAST
IMAGES OF SEMICONDUCTOR SITES VIA ONE-
PHOTON OPTICAL BEAM-INDUCED CURRENT
IMAGING AND CONFOCAL REFLECTANCE
MICROSCOPY

Filed: Herewith

Examiner: Not Yet Assigned

Art Unit: Not Yet Assigned

Confirmation No. : Not Yet Assigned

Customer No. : 27,623

Attorney Docket No.: 0002031USU/2280

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Dear Sir:

Prior to examination on the merits, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims begin on page 4 of this paper.

Amendments to the Abstract begin on page 7 of this paper.

Remarks begin on page 8 of this paper.